

Cont'd
Q2

(b) a modular optical inspection system including
a plurality of modular inspection subsystems each configured to detect defects on
a portion of a semiconductor wafer, [and]

a mechanism for moving at least one of the semiconductor wafer and the plurality
of modular inspection subsystems with respect to one another, and

a master processor configured to process data delivered from at least some of the
modular inspection subsystems, wherein a first one of the plurality of modular inspection
subsystems includes a local processor configured to process data collected by the first modular
inspection subsystem; and

(c) a handling tool for moving the semiconductor wafers among the plurality of
manufacturing tools and the inspection system.

REMARKS

Applicant believes that all pending claims are allowable and respectfully requests a
Notice of Allowance for this application from the Examiner. Should the Examiner believe that a
telephone conference would expedite the prosecution of this application, the undersigned can be
reached at the telephone number set out below.

Respectfully submitted,
BEYER & WEAVER, LLP



Jeffrey K. Weaver
Reg. No. 31,314

P.O. Box 61059
Palo Alto, California
(510) 843-6200